In-situ Atomic-scale Heating/Biasing System

Double-tilt
- α tilting up to ±25° *
- β tilting up to ±20° *

Multiple external field conditions
- Heating field
- Biasing field

Outstanding thermal and electrical application and measurement
- Wide temperature range (RT - 800°C)
- Ultra high heating precision (± 0.1°C*)
- Programmable heating
- Versatile biasing procedures
- pA-level measurement
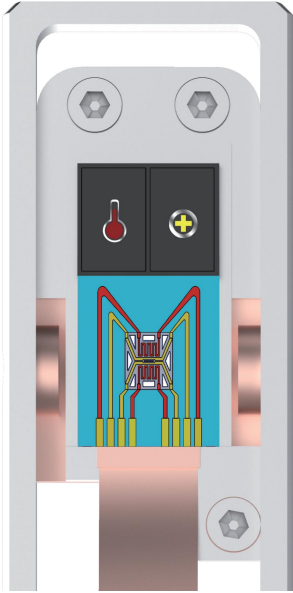
INSTEMS – TE
Heating / Biasing

COMPONENTS

① Double-tilt holder

② Mini Labs

③ Mini Lab Transfer box

④ Tool kit

⑤ PC, Software

⑥ Control Unit
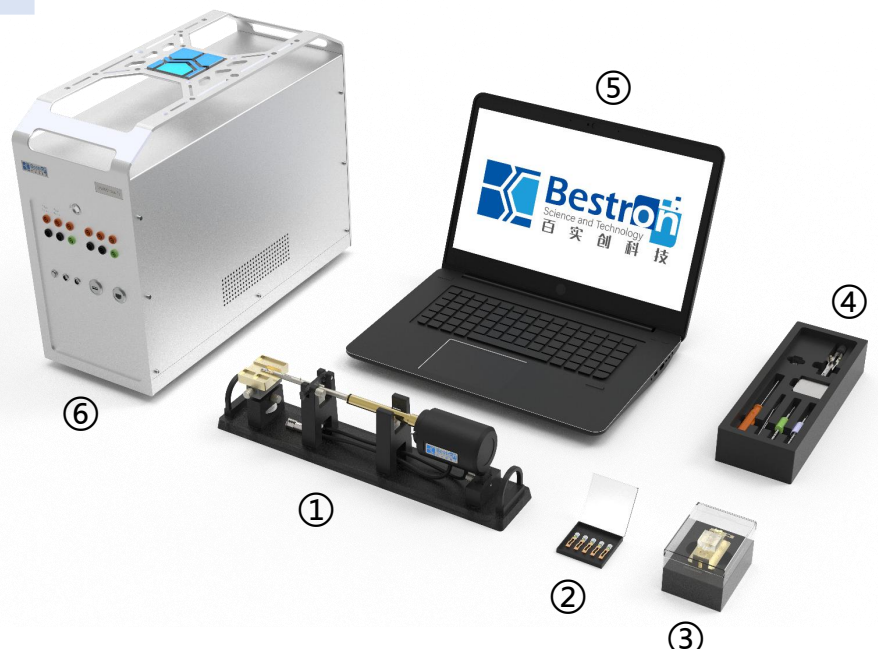
Note: The specifications listed in * depend on the TEM and the type of Mini lab.

SPECIFICATIONS

Heating	Temperature range	RT - 800°C
	Heating precision	± 0.1°C*
	Temperature measurement	Four-electrode method
	EDS	√
Biasing	Max output voltage	± 50 V *
	Current range	0 – 60 mA*
Double-tilt	Alpha (α) tilt	± 25° *
	Beta (β) tilt	± 20° *
	Accuracy	< 0.1°
Imaging	Spatial resolution	≤ 0.1 nm *
External field	Heating field, Biasing field	

ABOUT US

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Note: The specifications listed in * depend on the TEM and the type of Mini lab.